



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Group Art Unit: 1732

**Brian W. Baird, Michael J. Wolfe,
Richard S. Harris, Kevin P. Fahey,
Lian-Cheng Zou, and Thomas R. McNeil**

Application No. 10/017,497

Filed: December 14, 2001

For: **ULTRAVIOLET LASER ABLATIVE
PATTERNING OF MICROSTRUCTURES
IN SEMICONDUCTORS**

Date: February 4, 2005

Examiner: Dr. Stefan Staicovici

**I HEREBY CERTIFY THAT THIS CORRESPONDENCE
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PETITION FOR EXTENSION OF TIME UNDER 37 CFR § 1.136(a)

TO THE COMMISSIONER FOR PATENTS:

Applicants' attorney/agent hereby petitions that the time for response to the October 4, 2004 Office action, having a January 4, 2005 expiration date, be extended for a period of one month to February 4, 2005.

The enclosed check for the total fees includes the one-month time extension fee.

Respectfully submitted,

**Brian W. Baird, Michael J. Wolfe,
Richard S. Harris, Kevin P. Fahey,
Lian-Cheng Zou, and Thomas R. McNeil**

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By

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